



PTO/SB/08A (08-03)

Substitute for form 1449A/PTO		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number	10/791,633
		Filing Date	03/01/2004
		First Named Inventor	Maalouf, Khalil J.
		Art Unit	Not yet known
		Examiner Name	Not yet known
Sheet 1 of 3	Attorney Docket Number	019930-002510US	

U.S. PATENT DOCUMENTS+					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number Kind Code ² (if known)			
<i>Examiner: A1-A19</i>	A1	US-5,212,582	05-18-1993	Nelson	359/224
	A2	US-5,414,540	05-09-1995	Patel et al.	359/139
	A3	US-5,600,383	02-04-1997	Hornbeck	348/771
	A4	US-5,917,625	06-29-1999	Ogusu et al.	359/130
	A5	US-5,960,133	09-28-1999	Tomlinson	385/18
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	A7	US-5,999,672	12-07-1999	Hunter et al.	385/37
	A8	US-6,028,689	02-22-2000	Michalick et al.	359/224
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	A10	US-6,097,519	08-01-2000	Ford	359/130
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	A13	US-6,128,122	10-03-2000	Drake et al.	359/224
	A14	US-6,307,657 B1	10-23-2001	Ford	359/130
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	A16	US-6,480,320 B2	11-12-2002	Nasiri	359/291
	A17	US-6,501,877	12-31-2002	Weverka, et al.	385/31
	A18	US-6,541,831	04-01-2003	Lee et al.	257/415
	A19	US-6,597,048	07-22-2003	Kan	257/415

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Examiner Initials*	Cite No. ¹	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³	Number ⁴	Kind Code* (if known)				
	B1							<input type="checkbox"/>
	B2							<input type="checkbox"/>
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Examiner Signature	<i>[Signature]</i>	Date Considered	4/7/05
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Sheet	2	of	3	Attorney Docket Number	019930-002510US

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
bat	C1	Akiyama, T. et al.; "Controlled Stepwise Motion in Polysilicon Microstructures," Journal of Microelectromechanical Systems, Vol. 2, No. 3, September 1993; pp.106-110	
bat	C2	Andrew, et al., "Electrostatic Model for an Asymmetric Comdrive," Journal of Microelectromechanical Systems, Vol. 9, No. 1, March 2000, pp. 126-135	
bat	C3	Ashruf, C.M.A. et al., "Galvanic porous silicon formation without external contacts," Sensors and Actuators 74 (1999) pp. 118-122	
bat	C4	Bean, Kenneth et al., "Anisotropic Etching of Silicon," IEEE Transactions on Electron Devices, Vol. Ed-25, No. 10, October 1978	
bat	C5	Ciarlo, Dino R. "A latching accelerometer fabricated by the anisotropic etching of (110) oriented silicon wafers," Lawrence Livermore Nat'l Laboratory, March 1, 1992	
bat	C6	Dewa, A.S. et al., "Development of a Silicon Two-Axis Micromirror for an Optical CrossConnect," Solid State Sensors and Actuators Workshop, Hilton Head, South Carolina, pp. 93-96 6/2000	
bat	C7	Ford, Joseph et al., "Wavelength Add Drop Switching Using Tilting Micromirrors," Journal of Lightwave Technology, Vol. 17, No. 5, May 1999	
bat	C8	Grade, J. et al., "A Large-Deflection Electrostatic Actuator for Optical Switching Applications, Solid-State Sensor and Actuator Workshop, Hilton Head Island, South Carolina, June 4-8, 2000; pp. 97-100	
bat	C9	Kaajakari, V. et al.; "Ultrasonic Actuation for MEMS Dormancy-Related Stiction Reduction," In MEMS Reliability for Critical Applications, Proceedings of SAPIE Vol. 4180 (2000); pp. 60-65	
bat	C10	Keller, C. Dissertation entitled: Microfabricated Silicon High Aspect Ratio Flexures for In-Plane Motion; Fall 1998 (4/1998)	
bat	C11	Koch, T.L. et al., "Anisotropically etched deep gratings for InP/InGaAsP optical devices," J.App. Phys. 62 (8), 15 October 1987	
bat	C12	Muller, L. Dissertation entitled: Gimbaled Electrostatic Microactuators with Embedded Interconnects; Spring 2000 (4/2000)	
bat	C13	Nishi, I. et al., "Broad-Passband-Width Optical Filter for Multi-Demultiplexer Using a Diffraction Grating and a Retroreflector Prism," Electronics Letters, Vol. 21, No. 10, 9 th May 1985	
bat	C14	Phillippe, P. et al., "Wavelength demultiplexer: using echelette gratings on silicon substrate," Applied Optics, Vol. 24, No. 7, 1 April 1985	
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W	C17	Sun, Z.J. et al., Demultiplexer with 120 channels and 0.29-nm Channel Spacing," IEEE Photonics Technology Letters, Vol. 10, No. 1, January 1998	
	C18	Tang, W. et al., "Electrostatically Balanced Comb Drive for Controlled Levitation," Reprinted from Technical Digest IEEE Solid State Sensor and Actuator Workshop, June 1990, pp. 198-202	
W	C19	Torcheux, L. et al., "Electrochemical Coupling Effects on the Corrosion of Silicon Samples in HF Solutions," J. Electrochem. Soc., Vol. 142, No. 6, June 1995	
W	C20	VanKessel, P. et al., "A MEMS-Based Projection Display," Proceedings of the IEEE, Vol. 86, No. 8, August 1998; pp. 1687-1704	

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